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EUROPEAN PATENT APPLICATION

(21) Application number: 90200925.7

(51) Int. Cl.⁵: G03F 9/00

(22) Date of filing: 13.04.90

(30) Priority: 20.04.89 NL 8900991

(43) Date of publication of application:
24.10.90 Bulletin 90/43

(84) Designated Contracting States:
DE FR GB

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(54) Apparatus for projecting a mask pattern on a substrate.

(57) An apparatus for projecting a mask pattern (MA) on a substrate (W) by means of a projection lens system (PL) is described, which apparatus comprises a device for aligning a substrate alignment mark (P₁; P₂) with respect to a mask alignment mark (M₁; M₂), the projection lens system (PL) forming part of the alignment device. A correction element (25) is arranged in this system (PL) to compensate for the fact that this system (PL) is not optimised for the wavelength of the alignment beam (b).

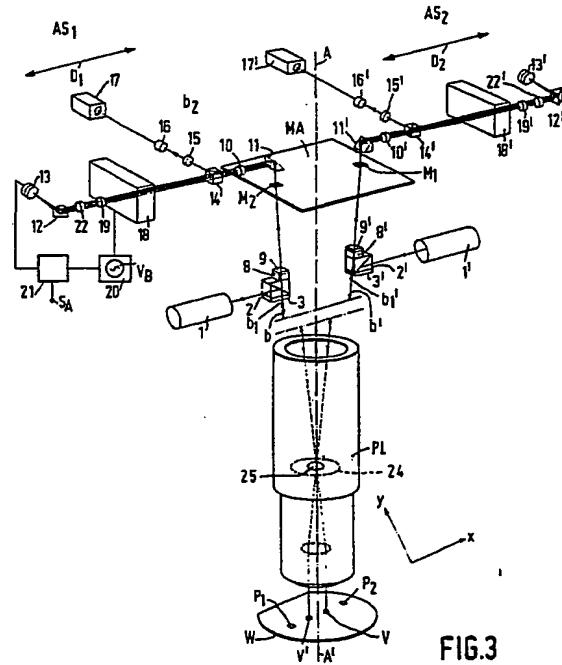


FIG.3



EP 90 20 0925

DOCUMENTS CONSIDERED TO BE RELEVANT									
Category	Citation of document with indication, where appropriate, of relevant passages	Relevant to claim	CLASSIFICATION OF THE APPLICATION (Int. Cl.5)						
D,A	EP-A-237109 (ASM LITHOGRAPHY) * pages 11 - 25; claim 10; figures * & US-A-4778275 ---	1, 3, 4, 7, 10 11, 13, 16-19	G03F9/00						
A	DE-A-1904504 (WESTERN ELECTRIC) * pages 5 - 9; figures * ---	1, 3							
D,A	DE-A-2608176 (LENINGRADSKI INSTITUT TOTSCHNOJ MECHANIKI I OPTIKI ET AL.) * page 11, last 3 lines - page 12, figures 4-7 * -----	12							
			TECHNICAL FIELDS SEARCHED (Int. Cl.5)						
			G03B						
<p>The present search report has been drawn up for all claims</p> <table border="1" style="width: 100%; border-collapse: collapse;"> <tr> <td style="width: 33%;">Place of search</td> <td style="width: 33%;">Date of compilation of the search</td> <td style="width: 34%;">Examiner</td> </tr> <tr> <td>THE HAGUE</td> <td>15 JUNE 1990</td> <td>HERYET C.D.</td> </tr> </table>				Place of search	Date of compilation of the search	Examiner	THE HAGUE	15 JUNE 1990	HERYET C.D.
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CATEGORY OF CITED DOCUMENTS		T : theory or principle underlying the invention E : earlier patent document, but published on, or after the filing date D : document cited in the application L : document cited for other reasons & : member of the same patent family, corresponding document							
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